

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application
Inventor(s): Tue Nguyen et al.
Appln. No.: 09/898,439
Confirm. No.: 1885
Filed: July 5, 2001
Title: PLASMA SEMICONDUCTOR PROCESSING
SYSTEM AND METHOD



PATENT APPLICATION

Art Unit: 2818
Examiner: Hoang, Quoc Dinh
Customer No. 23910

CERTIFICATE OF MAILING UNDER 37 C.F.R. § 1.8

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(Attorney Signature)
Sheldon R. Meyer, Reg. No. 27,660
Signature Date: 10/19/2004

RESPONSE TO OFFICE ACTION UNDER 37 C.F.R. § 1.111

Commissioner for Patents
P.O. Box 1450
Art Unit 2818
Alexandria, VA 22313-1450

Sir:

AMENDMENTS

This Response is in reply to the First Office Action July 14, 2004, setting a three-month period for response. This response therefore is timely.

Amendments to the Specification begin on page 2 of this paper.

Amendments to the Claims begin on page 3 of this paper.

Remarks/Arguments begin on page 9 of this paper.

Please amend the above-identified application as follows: